EE C247B/ME C218: Introduction to MEMS Design Lecture 5w: Process Modules I

Lecture Modules 3 & 4 on Process Modules online

Process Module Details lecture videos online

HW#1 due Thursday, 2/7 at 9 a.m.

Lecture 5: Process Modules I

Announcements:



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These give more details than I will give in class
  ♦ Watch these if your background in
                                                                  biffusion
    microfabrication is weak
                                                                  ♥ Ion Implantation
      -Very helpful for homework (& research)
                                                              • As stated earlier, this is now assumed knowledge
                                                                I will gloss over this material to review it a bit,
                                                                but will not go over it in detail
Today:
Reading: Senturia, Chapter 1
                                                                You can watch my lectures from EE245, Fall 2012
                                                                on the Webcast Berkeley site for more in depth

   Lecture Topics:

                                                                coverage: Lectures 6-8
  Benefits of Miniaturization
  Sexamples
                                                               Process Modulos
      -GHz micromechanical resonators
                                                               = there are actually only a few basic modules
      -Chip-scale atomic clock
                                                                    used for processing
      -Micro gas chromatograph

   Senturia, Chpt. 3; Jaeger, Chpt. 2, 3, 6

                                                                   Combination of these in the correct sequence
  Sexample MEMS fabrication processes
                                                                   yields an integrated circuit technology that
  ♦ Photolithography
  ♥ Etching
                                                                    provides transistor, MEMS, nonodoviros, etc.
  ♥ Oxidation
                                                                = For each module, need to understand:
  ♦ Film Deposition
                                                                  1) Physics and engineering of each module
   Diffusion
  ♥ Ion Implantation
                                                                      in datail.
                                                                  (2) Interaction between modules.
Last Time:
                                                                  (3) The offect of each module on the
Finished Chip-Scale Atomic Clock
Now, continue with Module 2 slides 30-48
                                                                       finished device.
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• Lecture Topics:

♥ Etching

Oxidation

CTN 2/5/19

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